

LCFI Report

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for LCFI collaboration

ILC VD Workshop, Menaggio, 23 April 2008

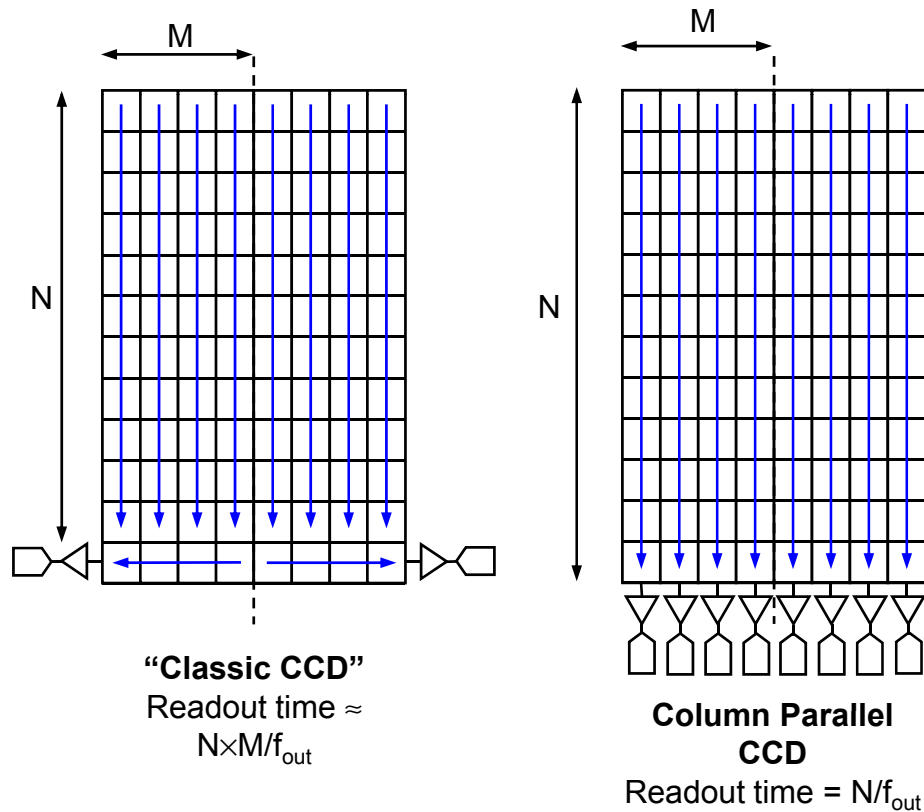
Outline

- CCD-based sensors
 - ◆ Column Parallel CCD
 - ◆ ISIS
- Driver and Readout chips for CPCCD

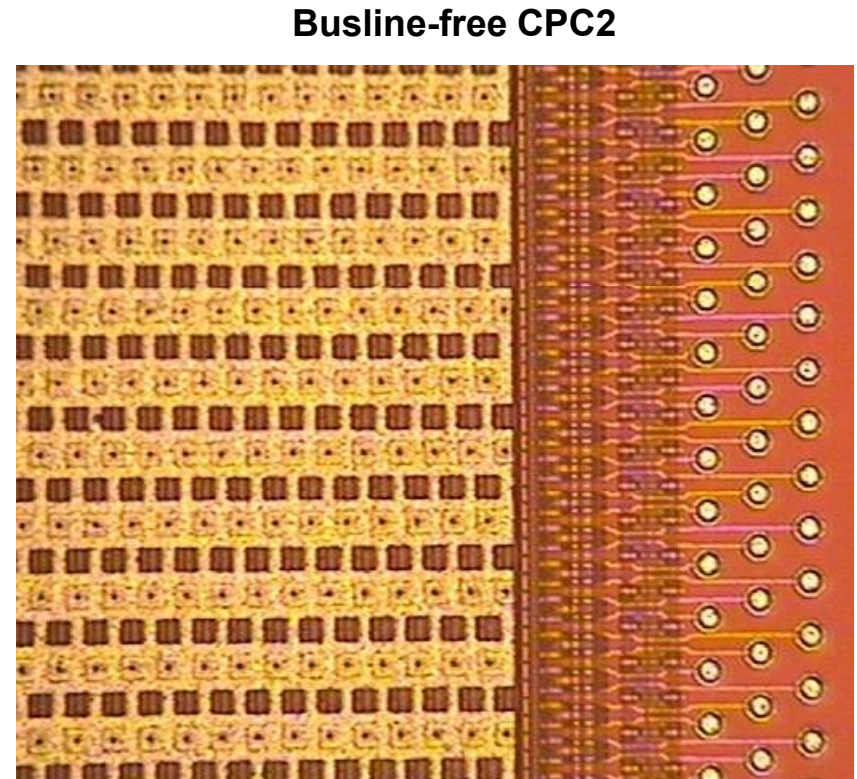
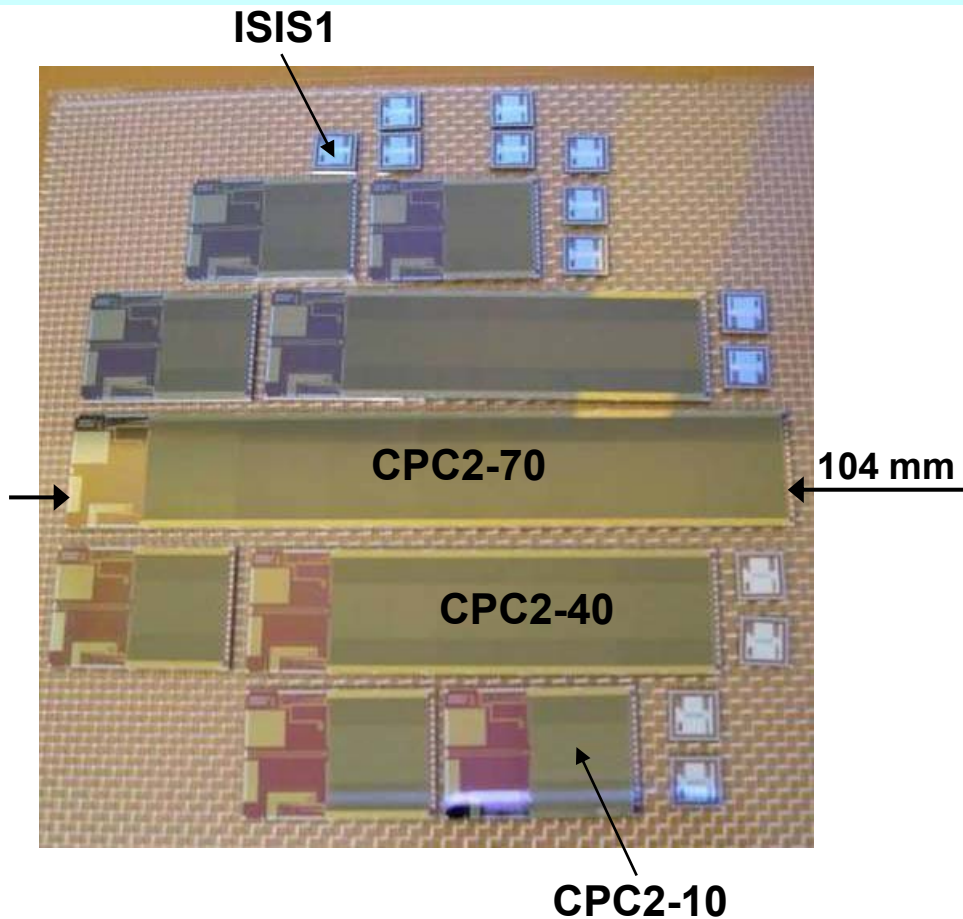
- Physics studies
- Mechanics

The Column Parallel CCD

- Every column has its own amplifier and ADC
- Readout time shortened by ~3 orders of magnitude
- All of the image area is clocked, complicated by the large gate capacitance
- Optimised for low voltage clocks to reduce power dissipation



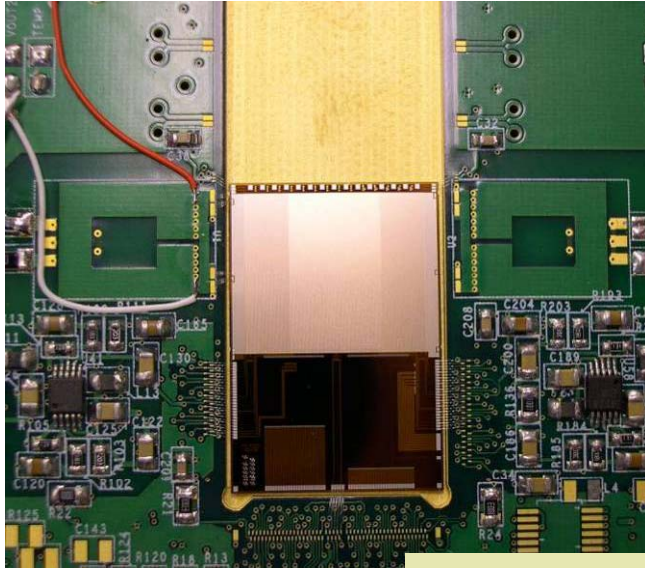
Our Second Generation CPCCD : CPC2



- CPC2 wafer (100 Ω .cm/25 μ m epi and 1.5k Ω .cm/50 μ m epi)
- Low speed (single level metallisation) and high speed versions

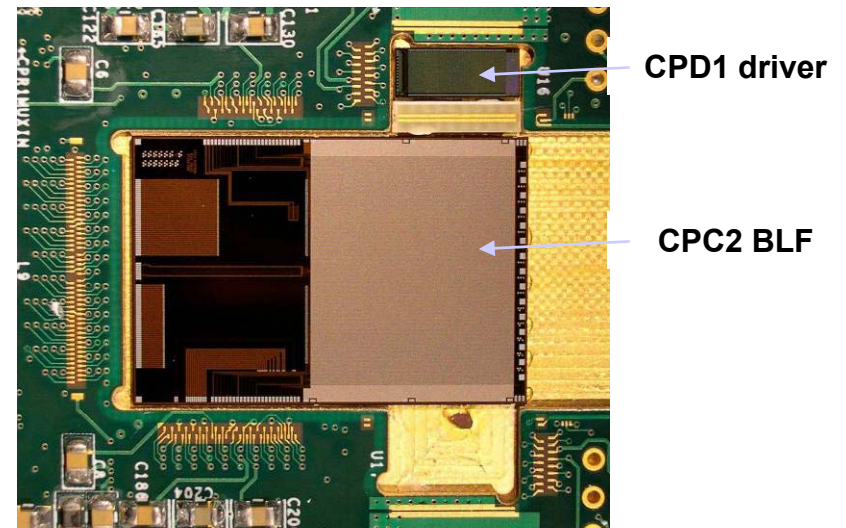
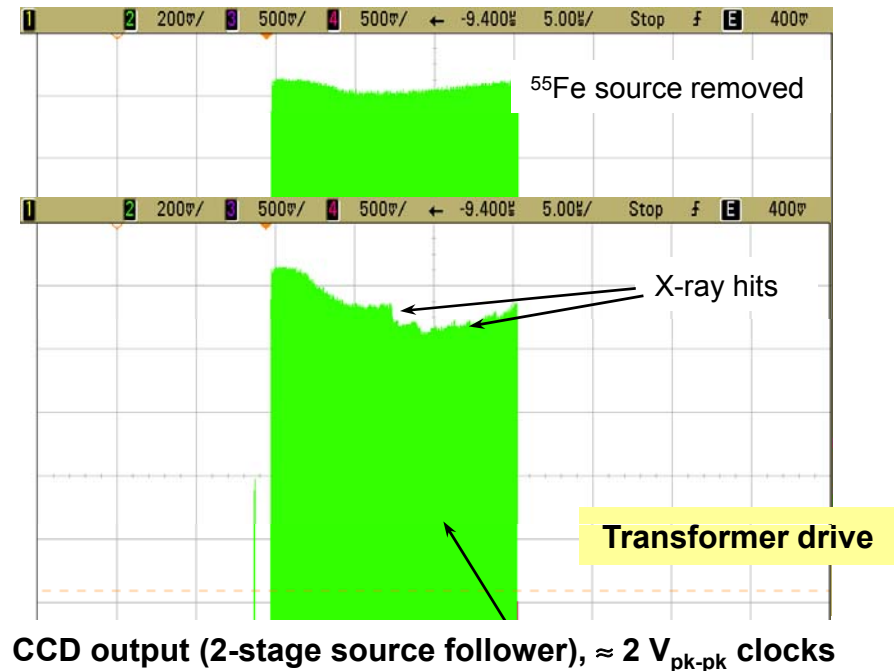
- High speed (busline-free) devices with 2-level metal clock distribution:
- ❖ The whole image area serves as a distributed busline
 - ❖ Designed to reach 50 MHz operation (needed to keep the occupancy < 1% in L1)

CPC2 – High Speed in Stand-alone Mode

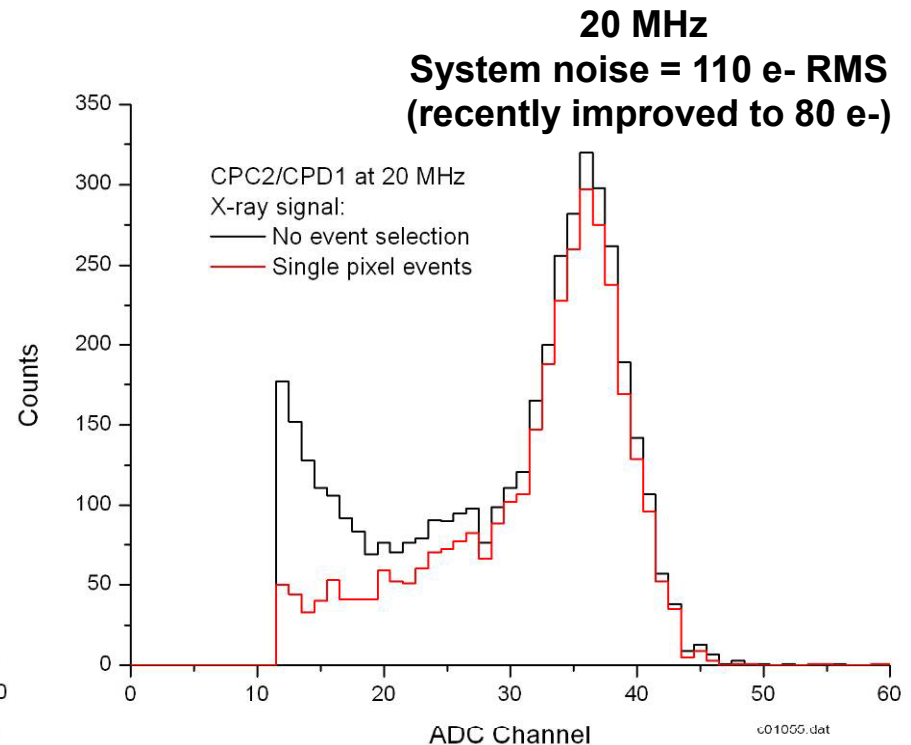
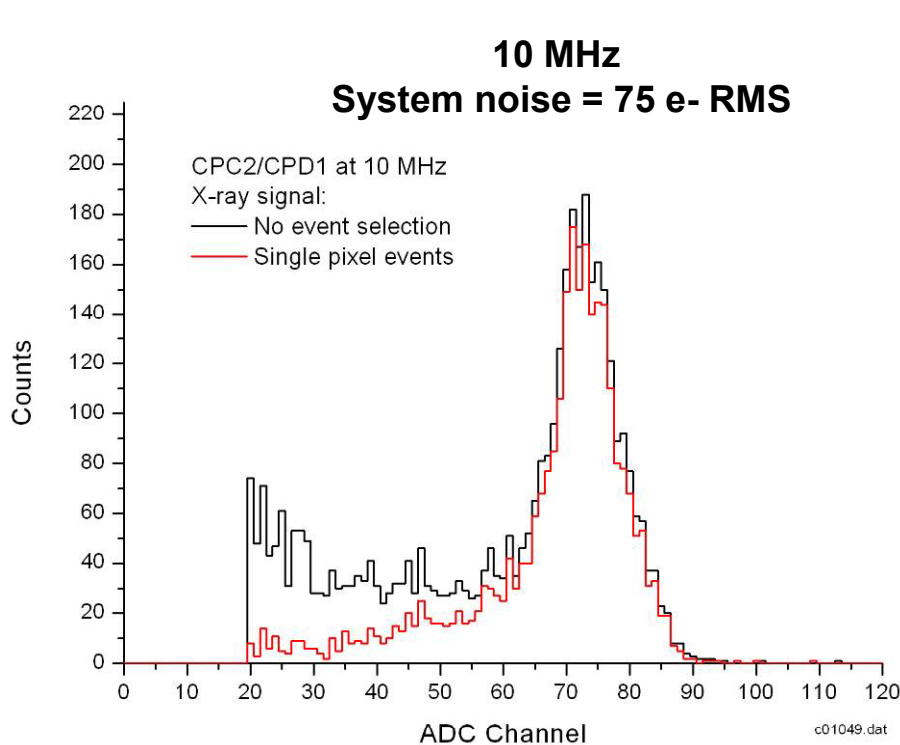


K.Stefanov, RAL
B.Hawes, Oxford

- First tests with a PCB transformer and a RF amplifier for clocking
- Busline-free CPC2-10 working at 45 MHz, important milestone
- Numerous parasitics diminish overall performance, high noise from the RF amplifier
- CMOS driver chip used as well



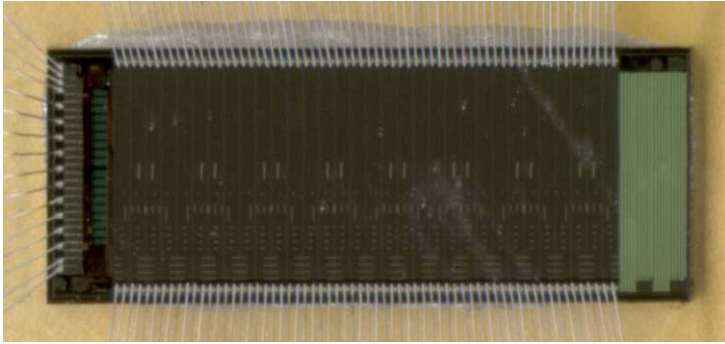
CPC2-10 BLF with CPD1 Clocking



- Stand-alone 2-stage source follower outputs
- ^{55}Fe signal (1620 electrons, MIP-like)
- CPD1 producing clocks in the range 3.3 V to 1.2 V
- Noise reduced from 200e- (with transformer drive) to 75 e- (CMOS driver)
- CPC2 works with clock amplitude down to 1.35 Vpp
- Tests are continuing – pushing up frequency, using 50 mm long sensor

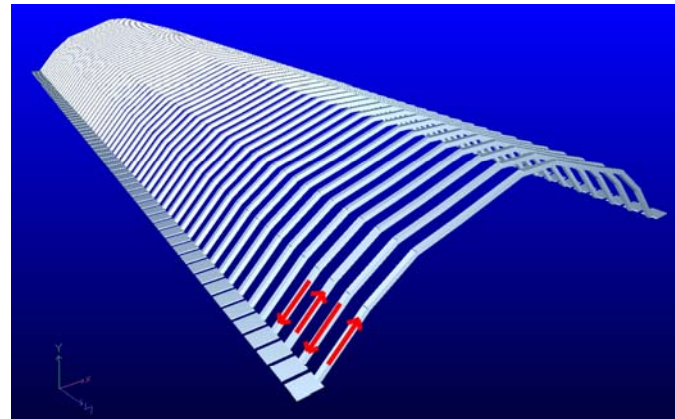
K.Stefanov

Clock Driver for CPC2: CPD1

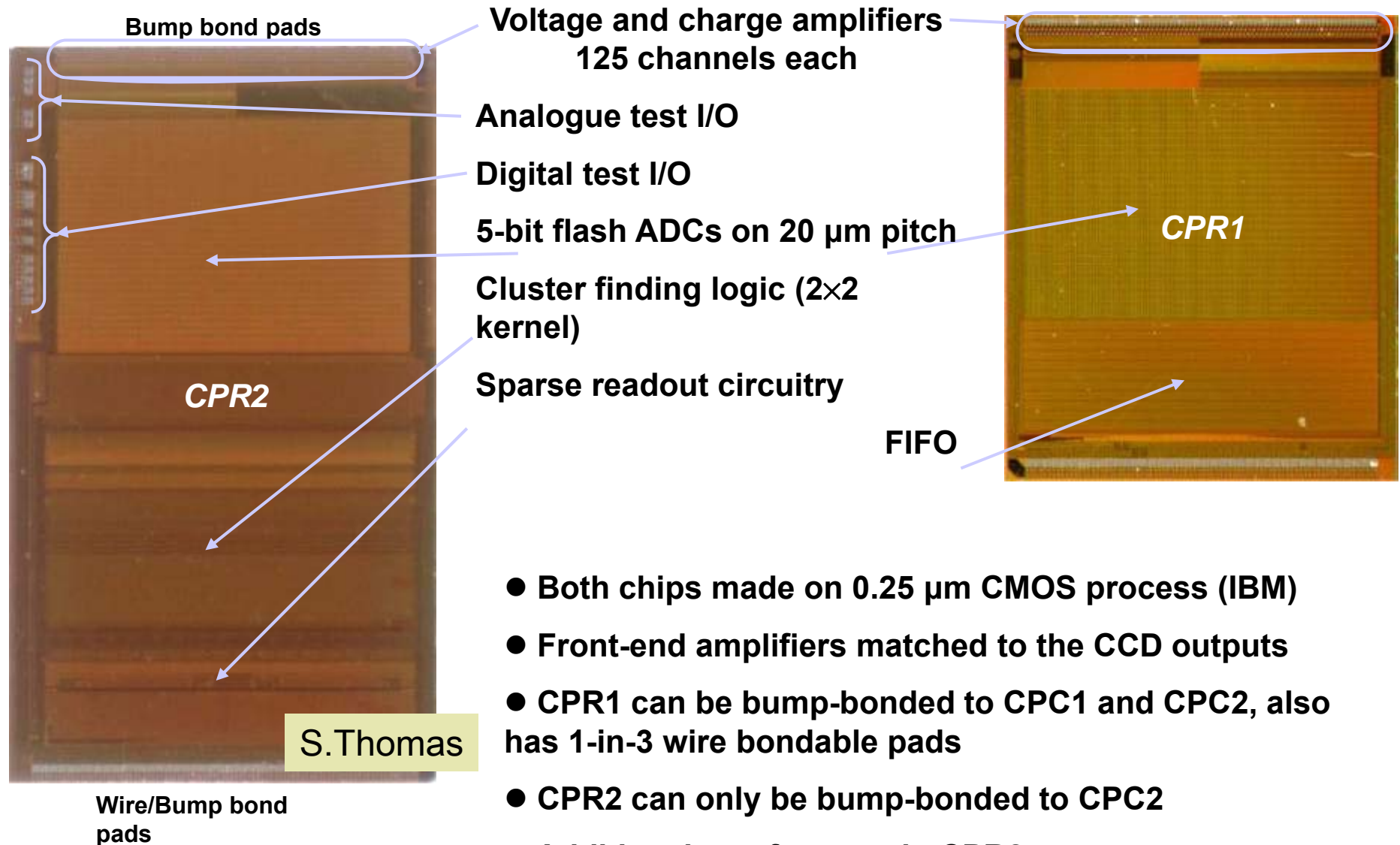


S.Thomas
P.Murray, RAL

- Designed to drive:
 - Outer layer CCDs (127 nF/phase) at 25 MHz
 - L1 CCD (40 nF/phase) at 50 MHz
 - CPC2 requires ~21 Amps/phase @ 2 V_{pp}
- One chip drives 2 phases, up to 3.3 V clock swing
- 0.35 μm CMOS process, chip size 3 × 8 mm²
- 8 independent clock sections
- Careful layout on- and off-chip to cancel inductance, **bump-bondable**
- Internal 2 nF load capacitor to one section
- **Works well up to 50 MHz**

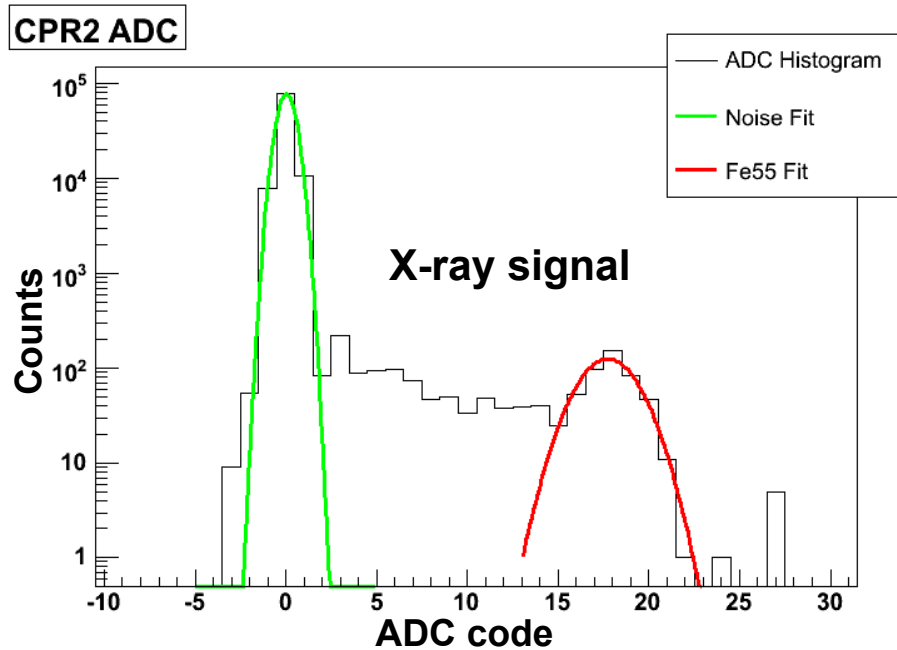


Readout Chips – CPR1 and CPR2

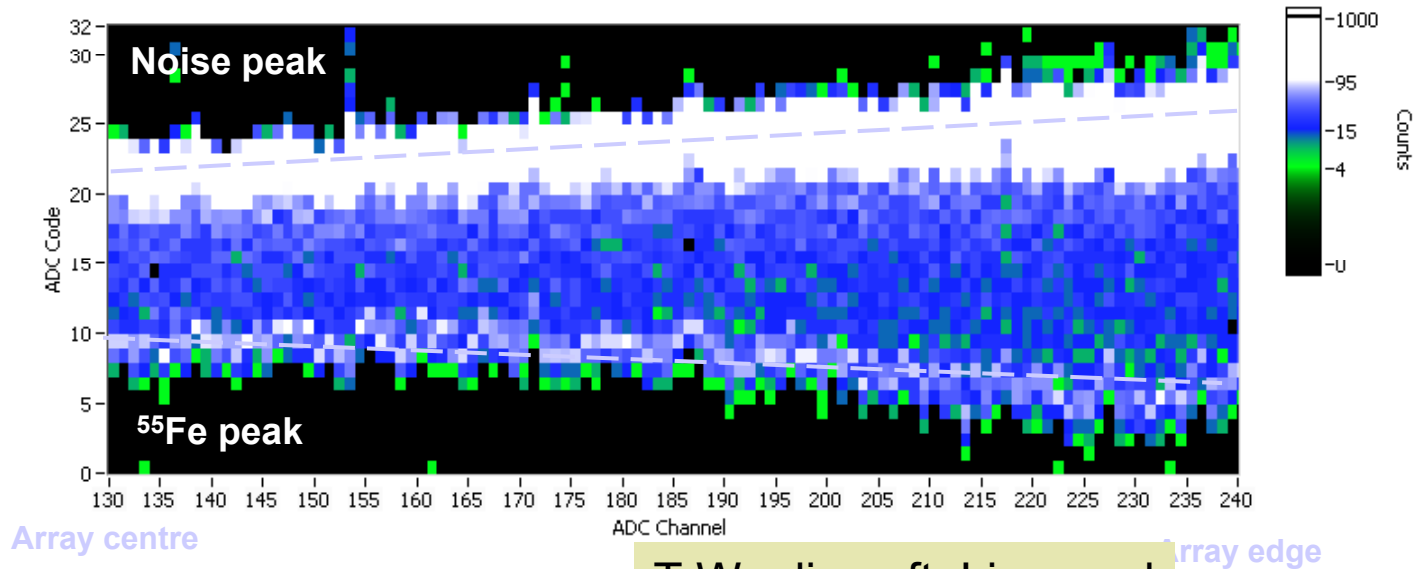


- Both chips made on 0.25 μm CMOS process (IBM)
- Front-end amplifiers matched to the CCD outputs
- CPR1 can be bump-bonded to CPC1 and CPC2, also has 1-in-3 wire bondable pads
- CPR2 can only be bump-bonded to CPC2
- Additional test features in CPR2

CPR2: Analogue Performance (1)

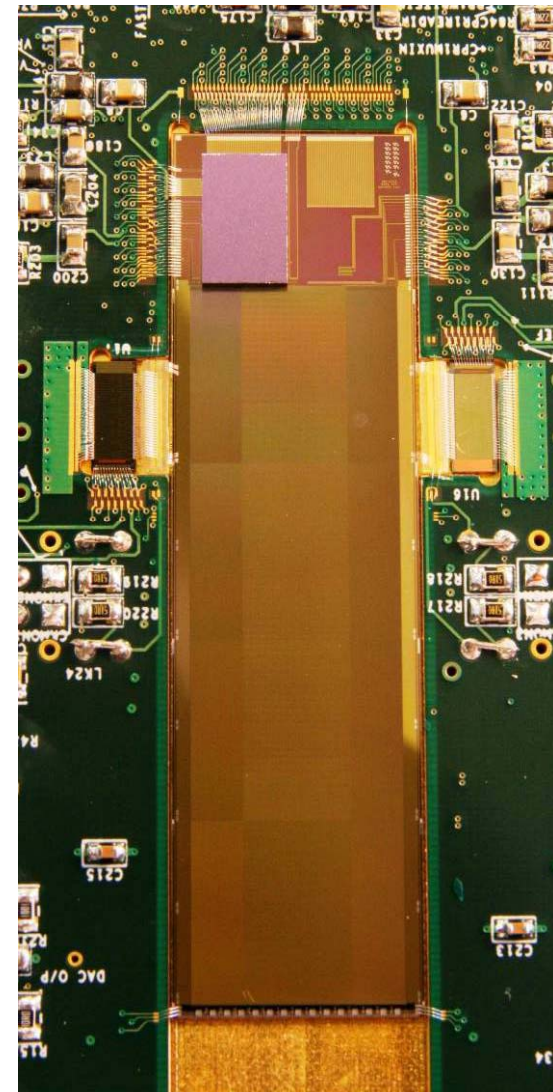
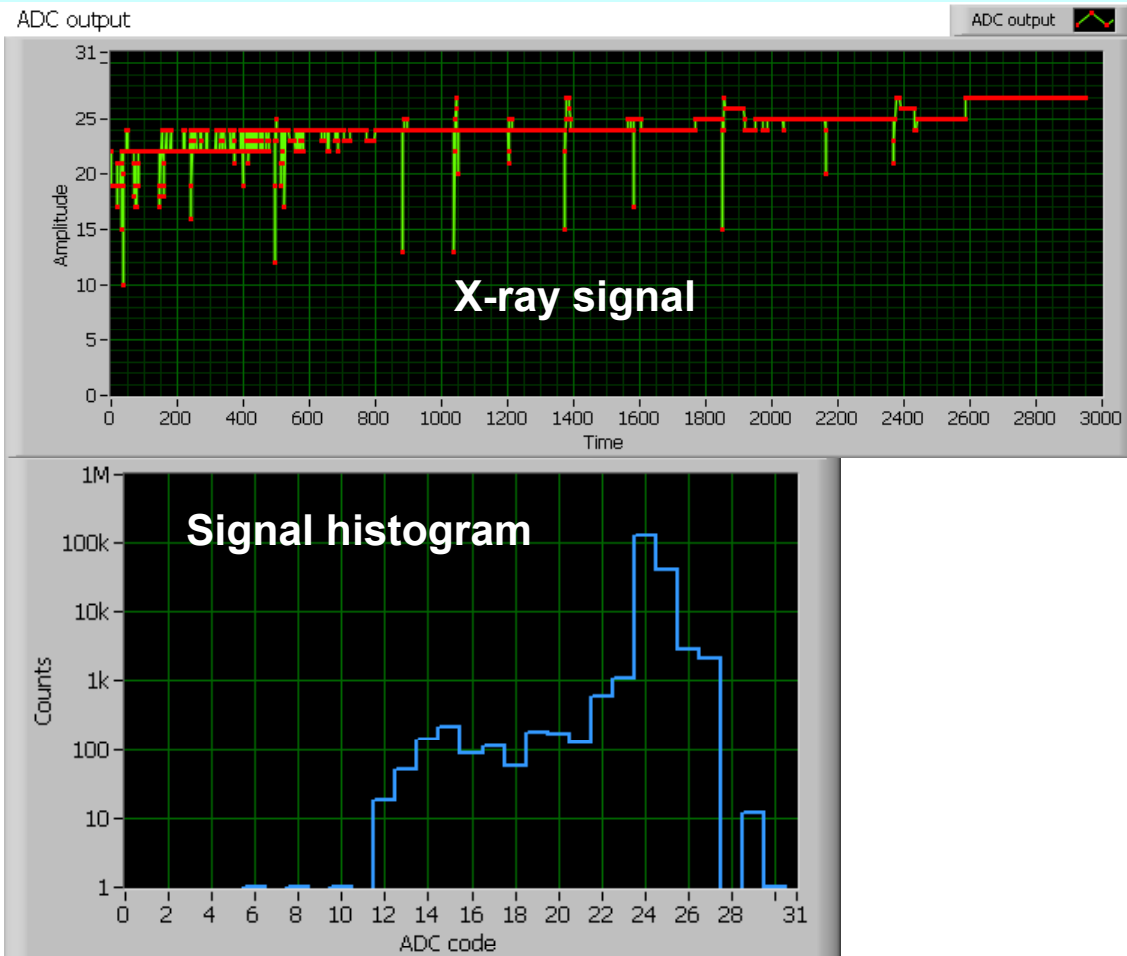


- Signals from **all** voltage channels observed (here at 2 MHz, 300 mV ADC range)
- Bump bond yield appears to be **100%**
- **Charge channels did not work** – possibly swamped by digital crosstalk from the ADCs
 - ❖ Complex mixed signal chip, difficult to design and simulate
- Gain decreases by 50% away from the chip edges (as in CPR1), under investigation
- Noise around 60 e-



T.Wooliscroft, Liverpool

CPR2: Analogue Performance (2)



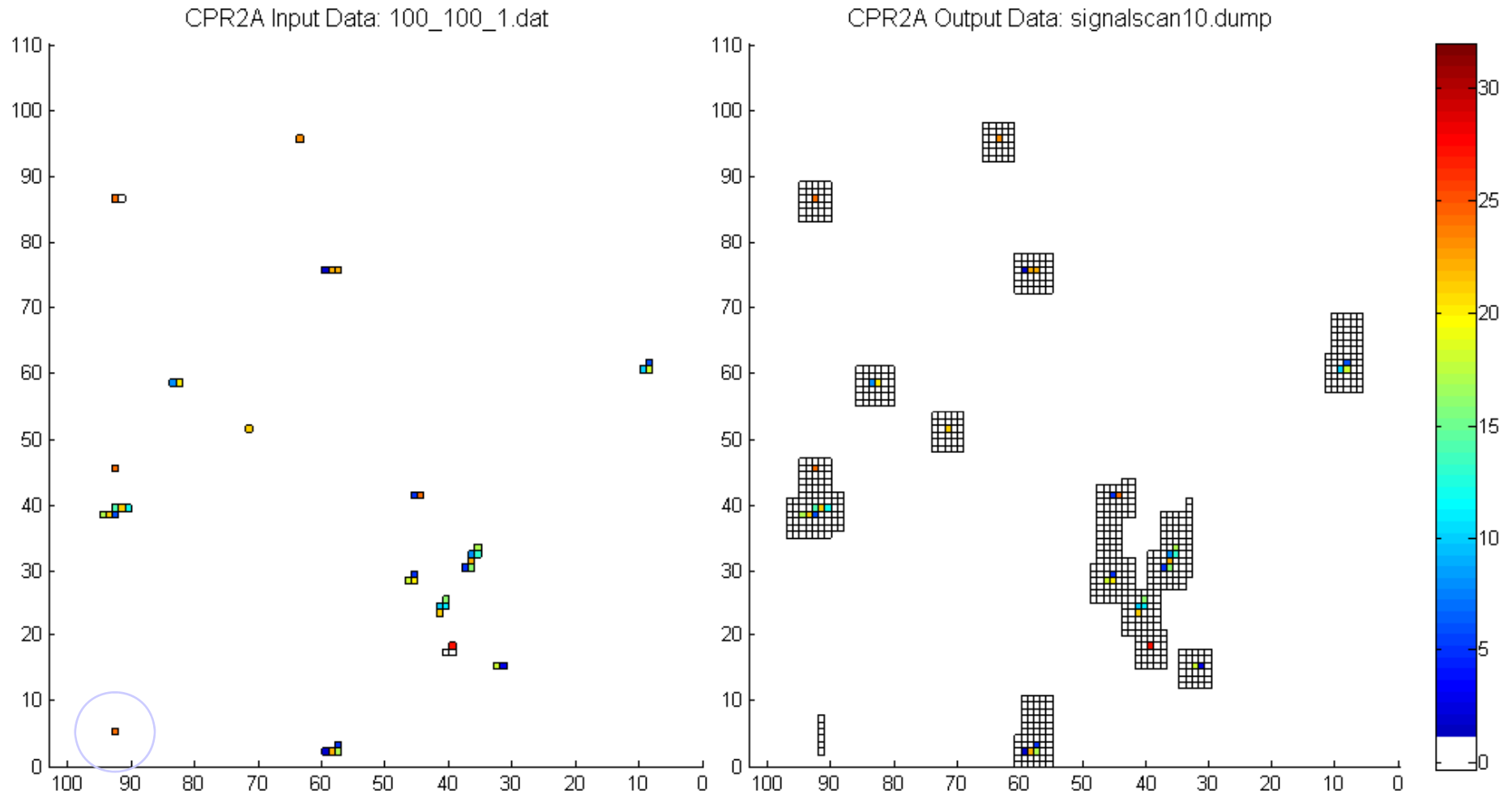
- Bump-bonded CPC2/CPR2 driven by two CPD1 chips
- Works up to 9 MHz

New Features in CPR2A

- **A range of improvements being implemented in the next generation chip CPR2A:**
 - ❖ **Cluster size reduced to 4×6**
 - ❖ **3-fold increase in the column memory buffer (can store up to 3 clusters) to reduce dead time and a new state machine**
 - ❖ **Individual column threshold – corrects for gain variations**
 - ❖ **Analogue calibration circuit – the chip can be partially tested without bump bonding to a CCD**
 - ❖ **Improvements to the analogue circuitry: gain matching, reduced differential non-linearity in the ADC, new clock distribution**
 - ❖ **Digital crosstalk to the charge amplifiers will be minimized**
 - ❖ **Code-dependent current in the ADC will be reduced**

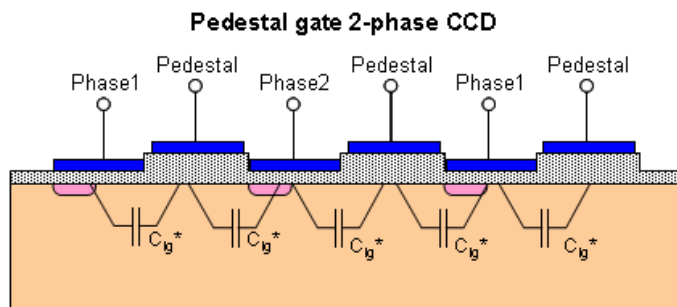
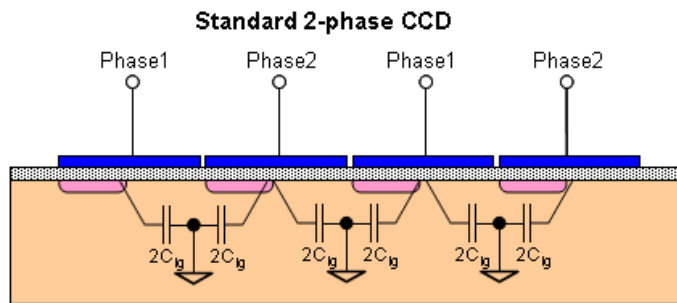
- **CPR2A received a week ago, being diced now – tests will start soon**

Sparsification with Realistic Data in CPR2A

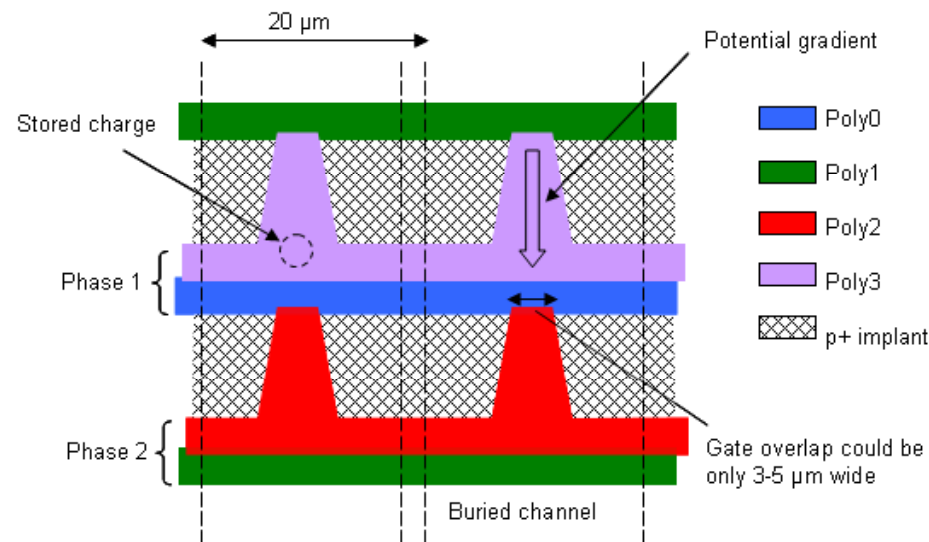


- ❖ Near-perfect readout over 100 time steps (44 hit pixels, occupancy 0.44%)
- ❖ One missing data point in the output (channel 92, time stamp 4)

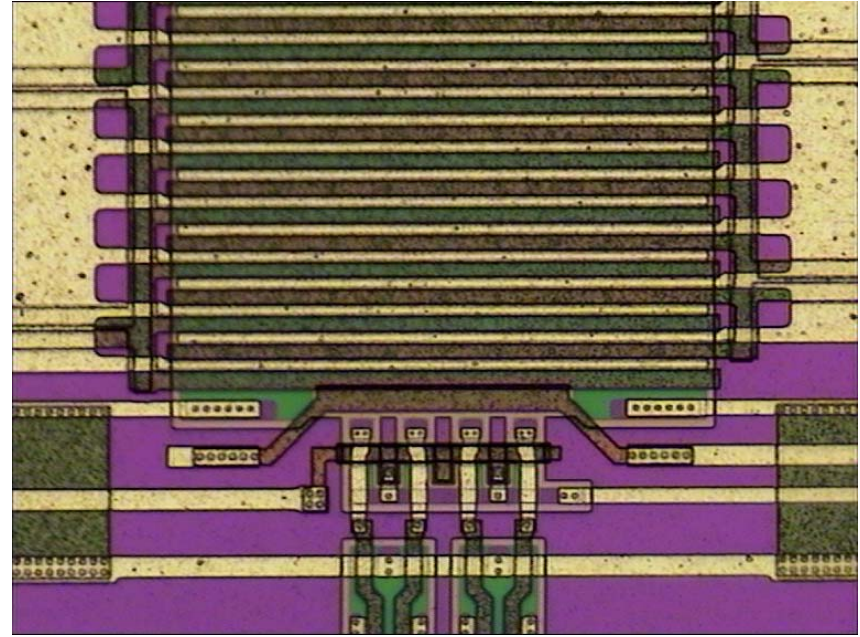
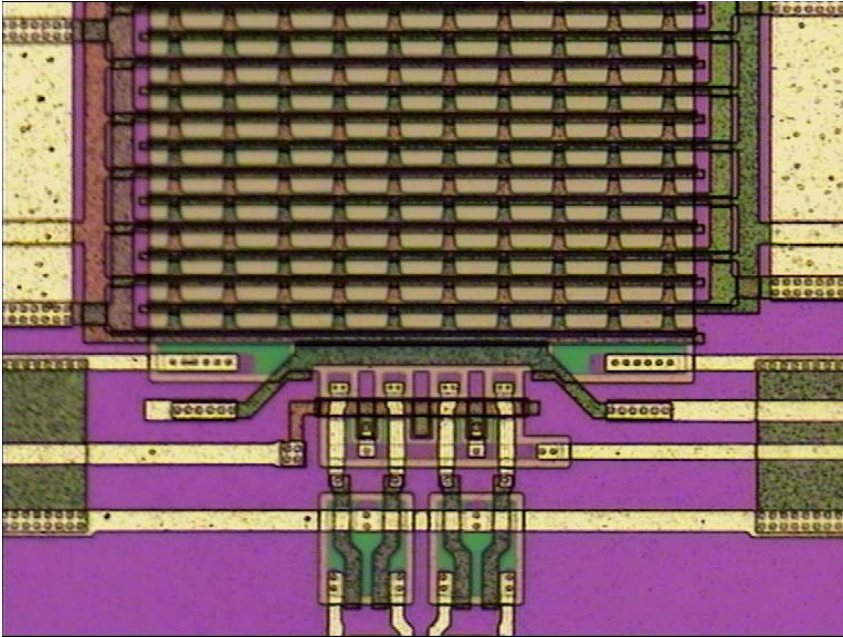
CPC-T



- **Two-fold goal : lower V and lower C**
- **Two designs based on CPC2 to study very low inter-gate barriers and clock amplitudes**
- **Six designs for reduction of the inter-gate capacitance:**
 - Pedestal CCD (on 20 μm and 24 μm pitch)
 - Shaped Channel CCD (variant of the Pedestal CCD), on 20 μm and 24 μm pitch
 - Open Phase CCD
 - “Inter-channel gap” CCD
 - Pedestal designs could reduce C_{ig} by a factor of

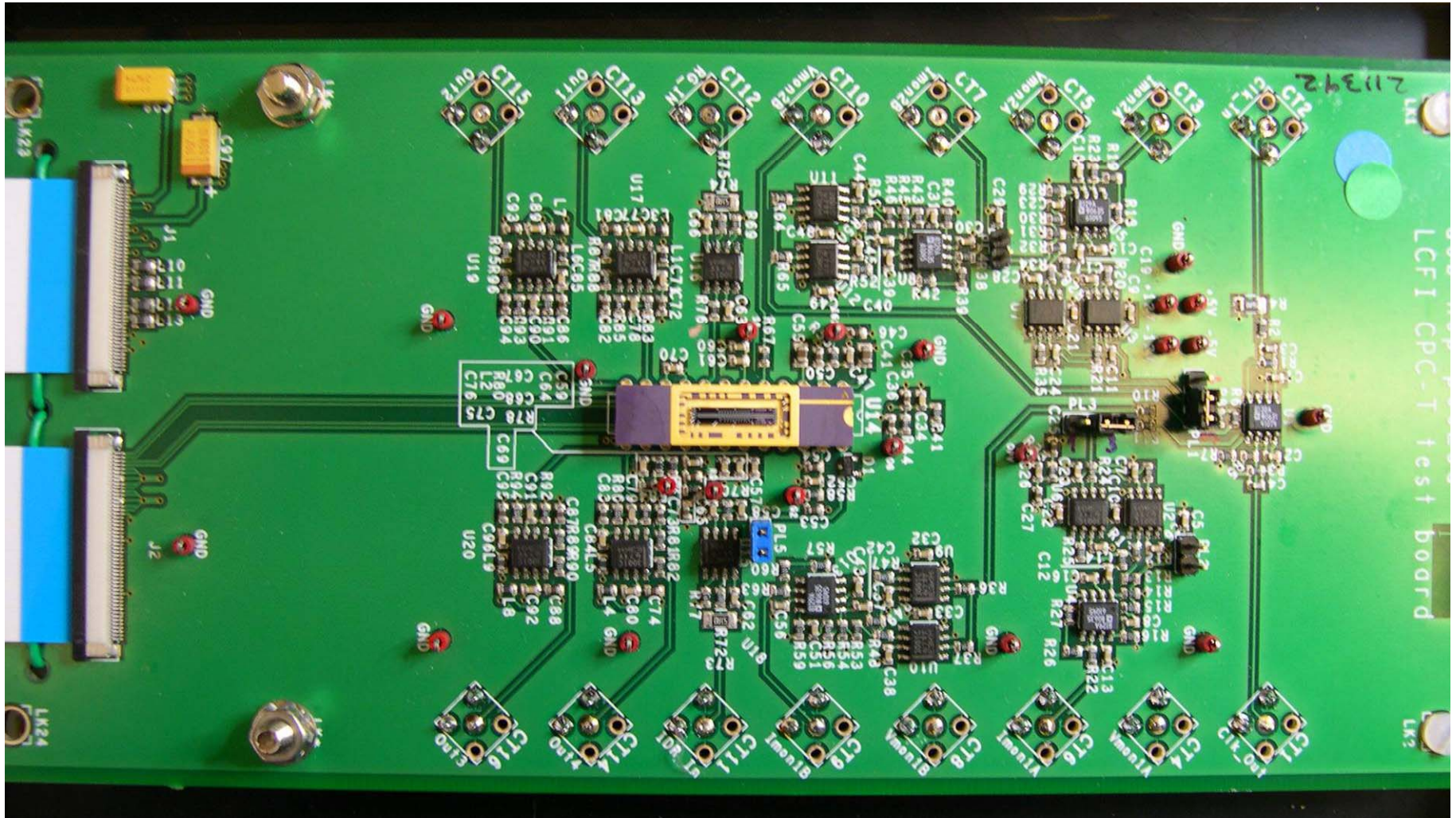


CPC-T



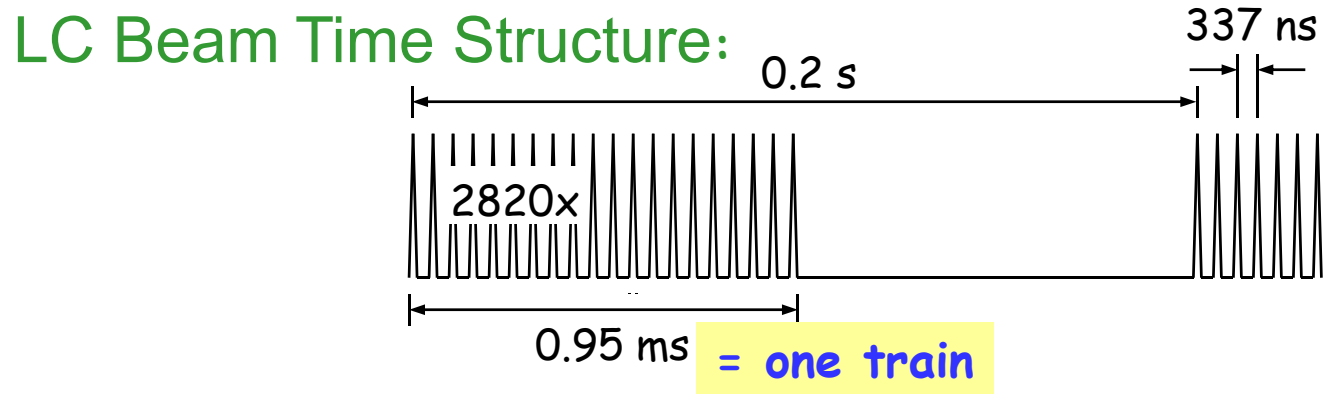
- 6 CPC-T wafers delivered, one of each type
- One type (stepped nitride barrier) failed the complete wafer
- Tests started at RAL and Oxford – the chip works!

CPC-T in its board



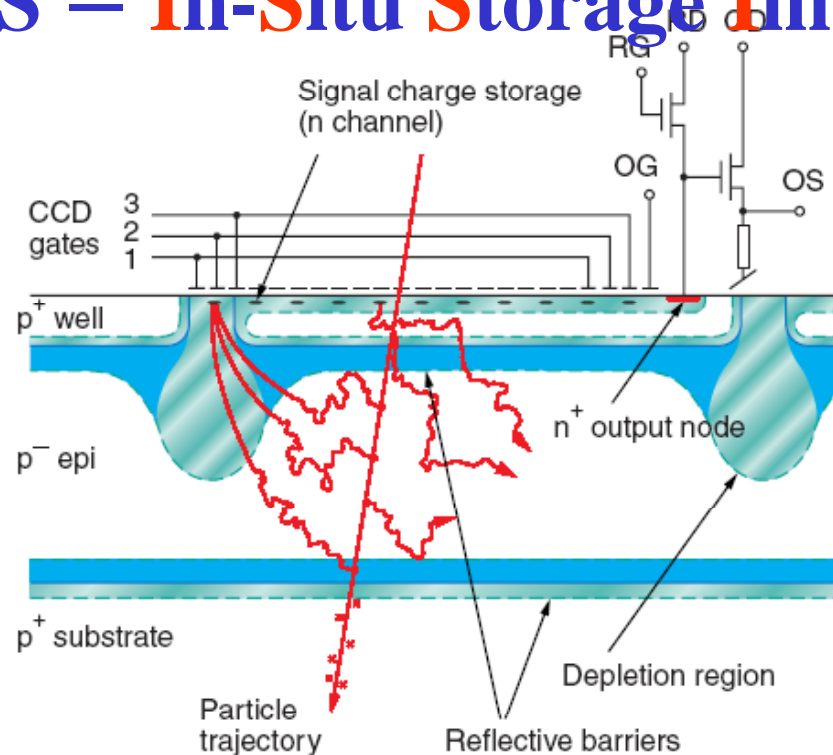
D.Cussans, Bristol

Readout for ILC



- Massive e^+e^- background from beamstrahlung : pairs radiated in intense EM fields of bunches
- Need to read out pixels in vertex detector once occupancy = 1%
 - ◆ 20 times per train
- **Main idea: Each pixel has a 20-cell storage**
 - ◆ Charge is stored **INSIDE** the pixel during collisions and read out during quiet time

ISIS – In-Situ Storage Image Sensor

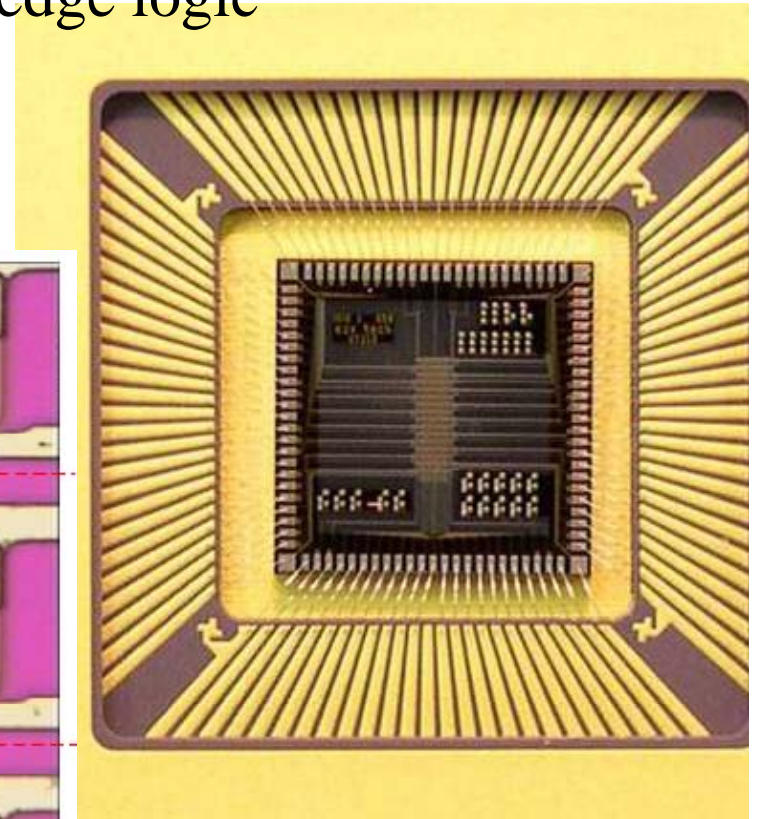
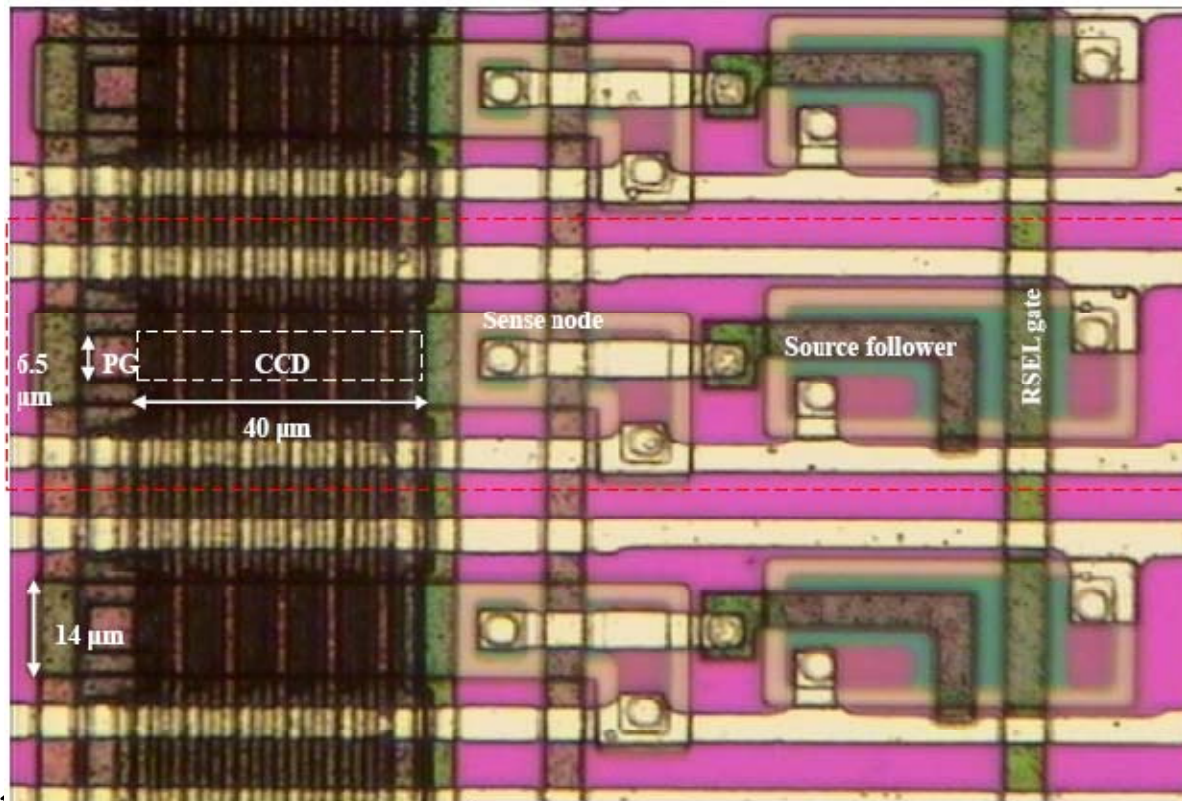


Ch.Damerell

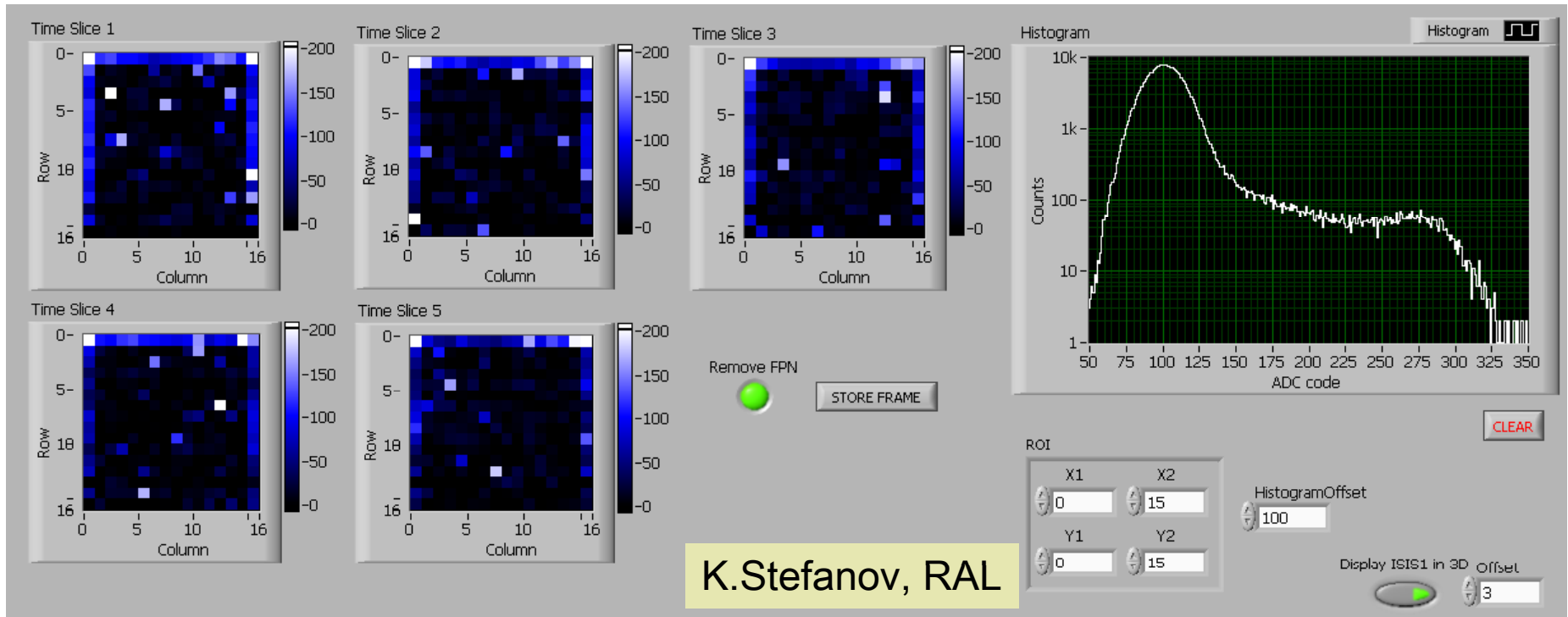
- Each pixel has internal memory implemented as CCD register
 - ◆ Charge collected under a photogate
 - ◆ Charge is transferred to 20-pixel storage CCD in situ
 - ◆ Conversion to voltage and readout in the 200 ms-long quiet period after collisions
- Visible light imagers based on the ISIS principle are available off-the-shelf (ex. DALSA, 100 MHz camera with 16 storage cells)

The ISIS1

- 16x16 pixels, each $140 \times 60 \mu\text{m}^2$
- Five storage cells for pixel
- Direct access to pixels by Row Select, no edge logic
- Two variants : with and without p-well
- Produced by e2V in UK
 - ◆ e2V had to rerun the p-well variant



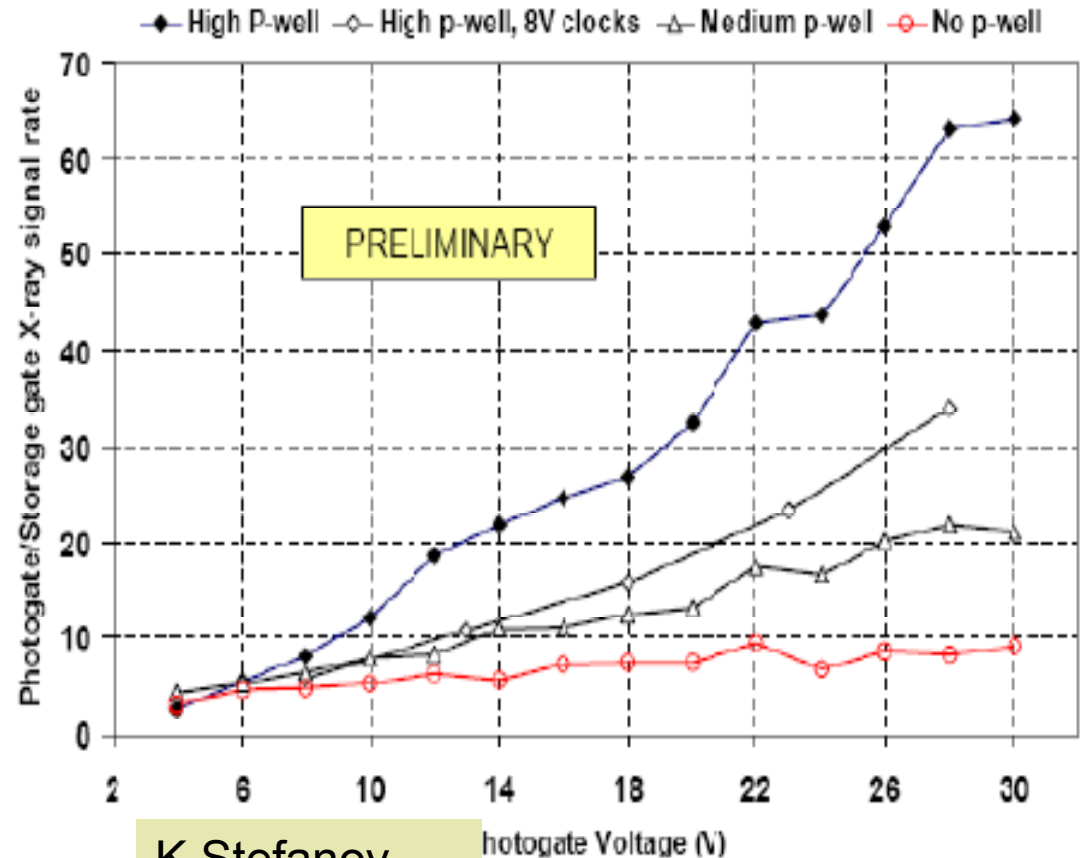
ISIS Proof of Principle



- Tests with ^{55}Fe X-ray source
 - ◆ Demonstrated correct charge storage in 5 time slices and consequent readout

ISIS1 with p-well

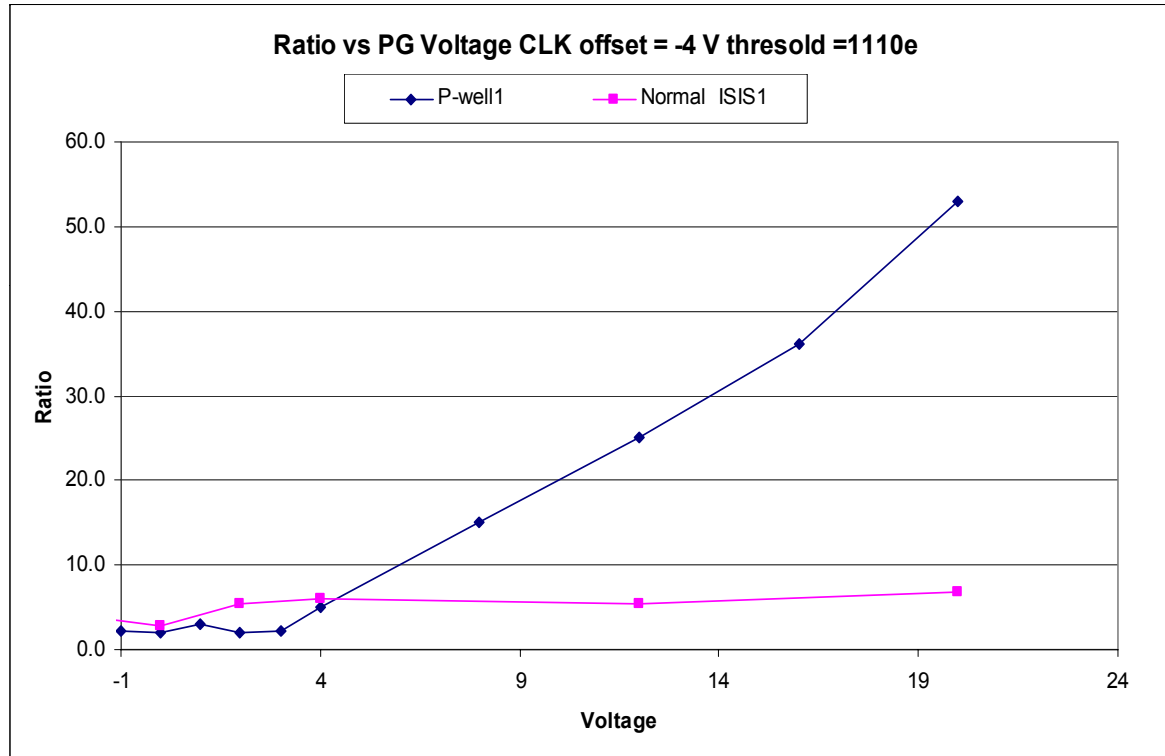
- High p-well doping protect storage register
- Look at ratio R of charge collected at photogate to charge collected at storage pixel
 - ◆ From ^{55}Fe (1640 e⁻)
- If increase clock voltage, get punchthrough under in-pixel CCD, R drops
- Lower p-well doping, charge reflection decreases
- No p-well, R ~ 7
 - ◆ dependent on gate geometry and voltages



K.Stefanov
G.Zhang, RAL

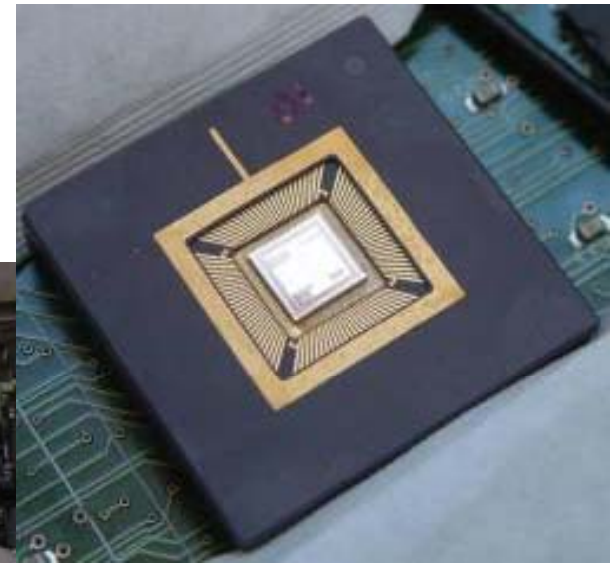
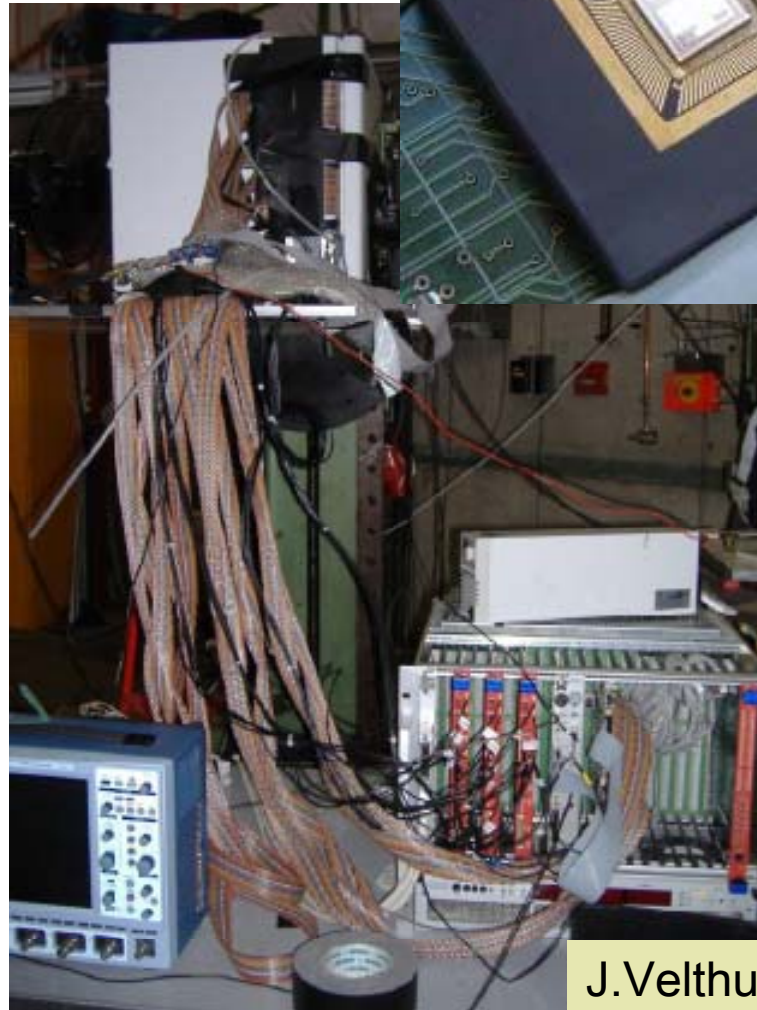
ISIS1 (p-well)

- Direct punch-through observed too (below):



ISIS1 Testbeam

- Constructed telescope with five ISIS1 chips
 - ◆ No p-well
- Active area $0.56 \times 2.22 \text{ mm}^2$
 - ◆ Accurate alignment required
- Tests performed at DESY 1-6 GeV electron beam in Nov 2007
- Readout speed 2.5 MHz
 - ◆ ILC needs 1 MHz

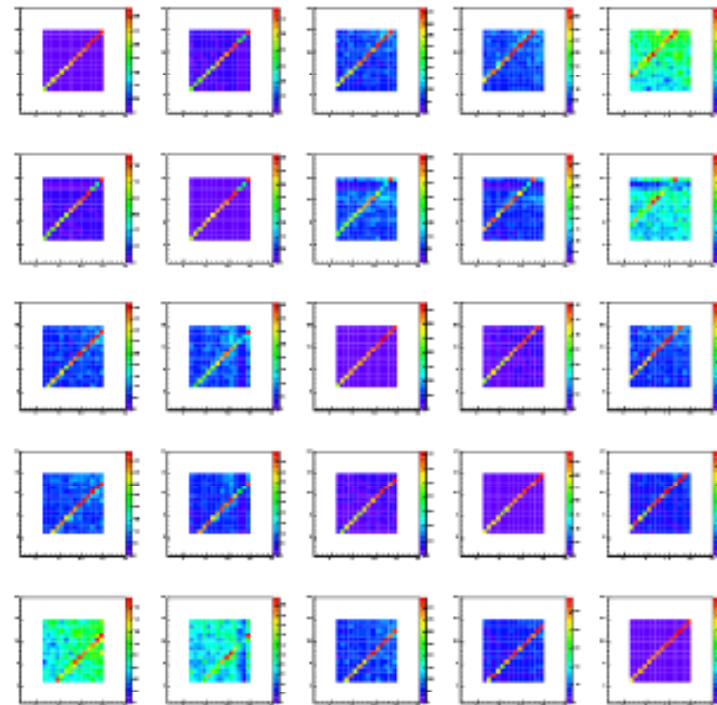


J.Velthuis
J.Goldstein
S.Mandry, Bristol

Test Beam First Results

- $S/N = 37$
- Position resolution in x-direction $10.8 \mu\text{m}$
 - ◆ Pitch $60 \mu\text{m} \rightarrow$ some charge sharing
 - ◆ Included large multiple scattering
- Little charge sharing in y-direction ($140 \mu\text{m}$ across pixel)
- Next testbeam in August at CERN
 - ◆ Large beam energy and EUDET telescope
- Will test ISIS1 with p-well

■ x versus x (“short” direction).



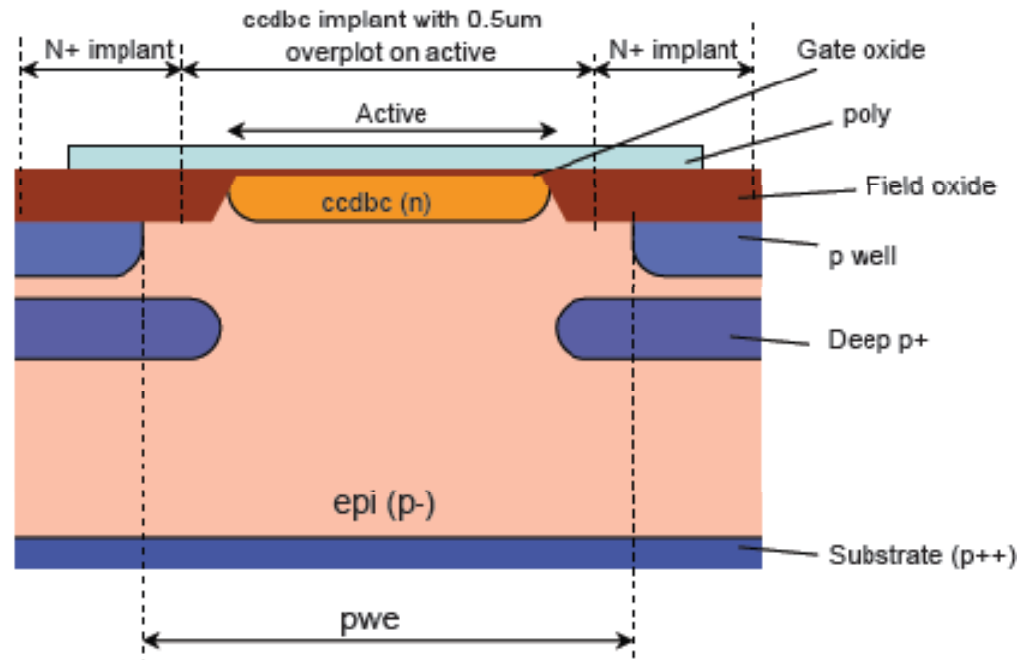
Correlation between measured and predicted position

J.Velthuis, Bristol

Next generation ISIS: ISIS2

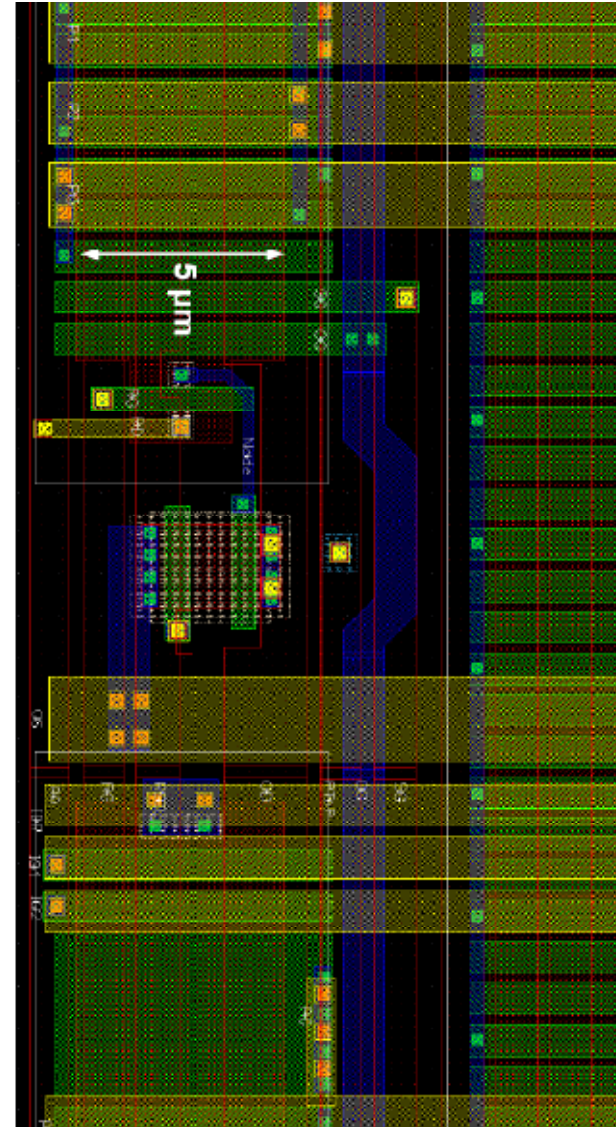
- Jazz Semiconductor will manufacture ISIS2
 - ◆ Process: 0.18 μm with dual gate oxide \rightarrow possible voltages 1.8V and 5 V
 - ◆ p++ wafers with 25 μm epi layer $\rho > 100 \text{ Ohm cm}$
 - ◆ Area 1 cm^2 (four 5x5 mm^2 tiles)
- Will develop buried channel and deep p+ implant
 - ◆ Buried channel is necessary for CCD
 - ◆ Non-overlapping gates
 - ◆ Deep p+ is beneficial to decouple buried channel from p-well, no need for punchthrough, was absent in ISIS1

- Cross section under Photogate:



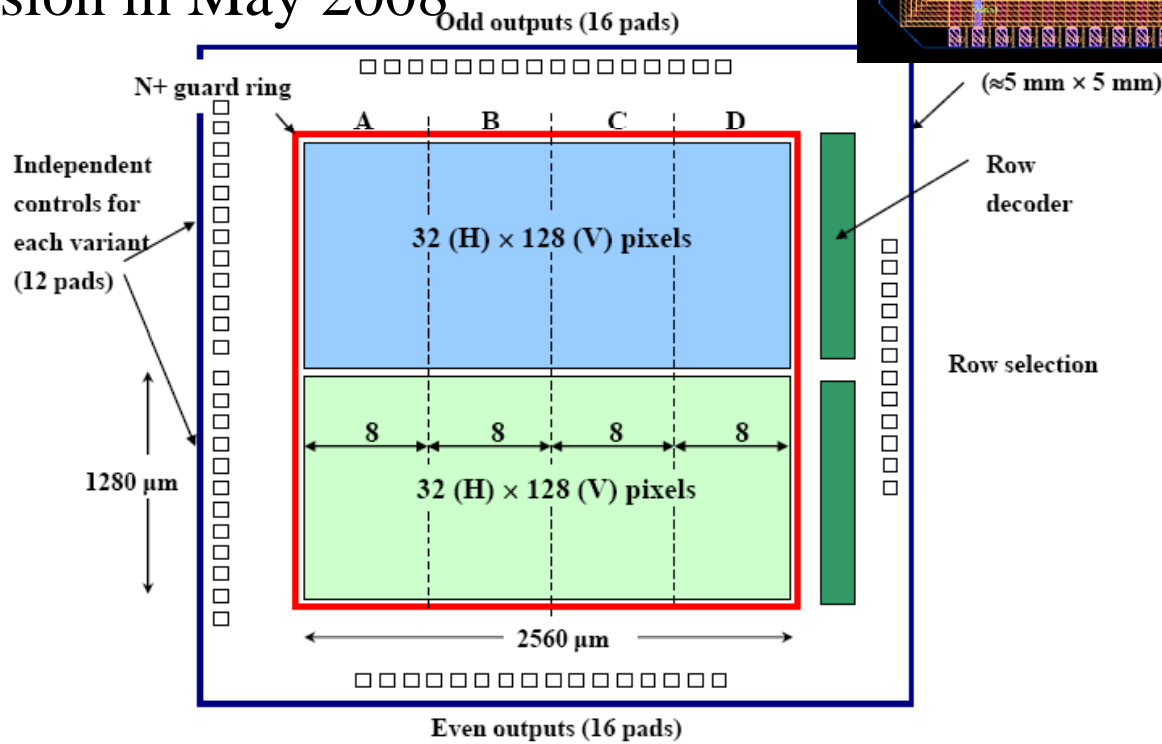
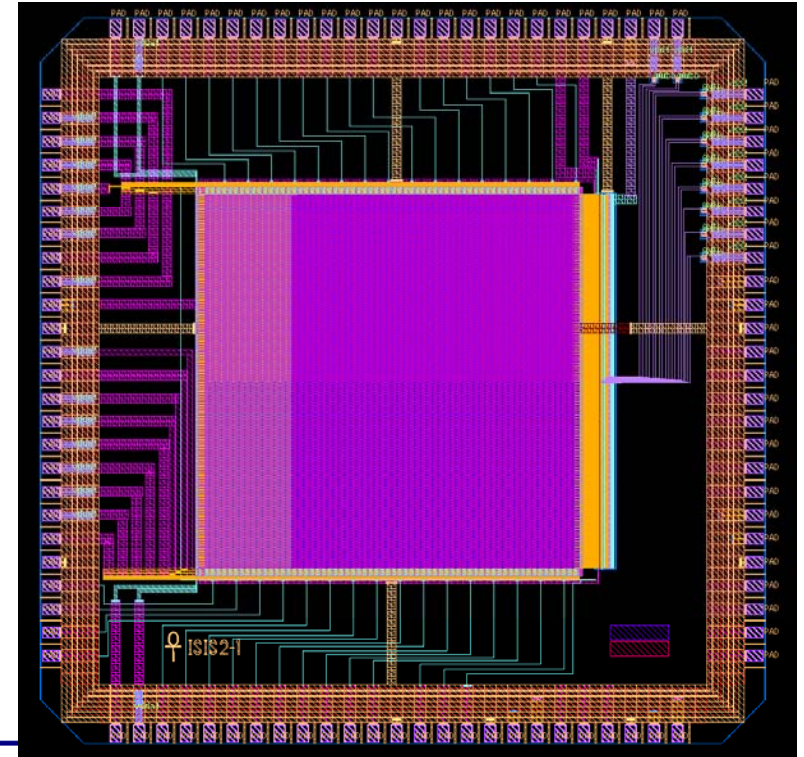
ISIS2 Design

- Pixels $80 \times 10 \mu\text{m}^2$
- Buried channel $5 \mu\text{m}$ wide
- 3 metal layers
- CCD gates: doped polysilicon
- Logic, source follows use 5V custom logic gates



ISIS2 Design

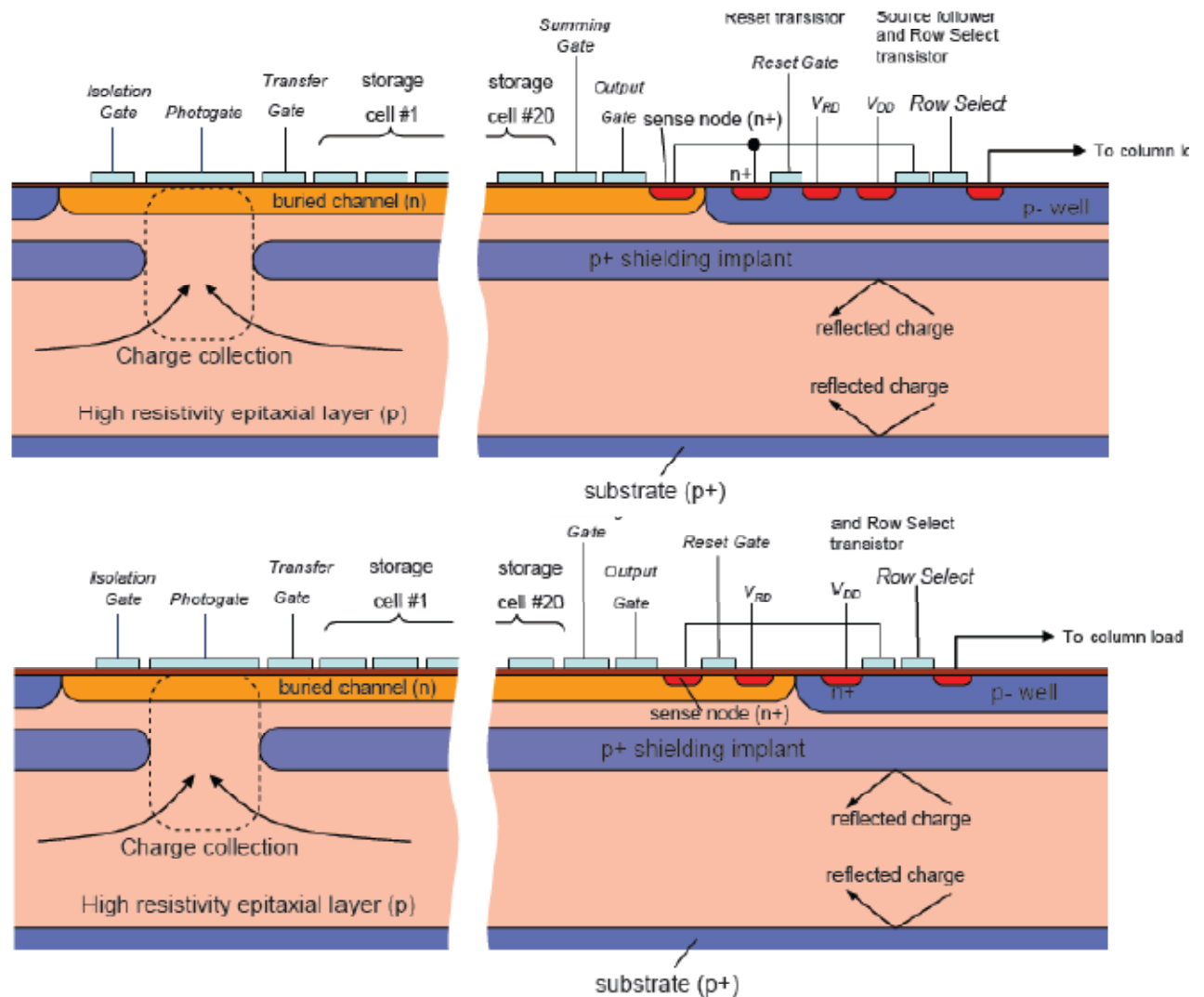
- One chip will have several variants of ISIS2
 - ◆ Each has independent control
- Row select and decoder edge logic
- Will have several test structures
- Submission in May 2008



K.Stefanov
P.Murray, RAL

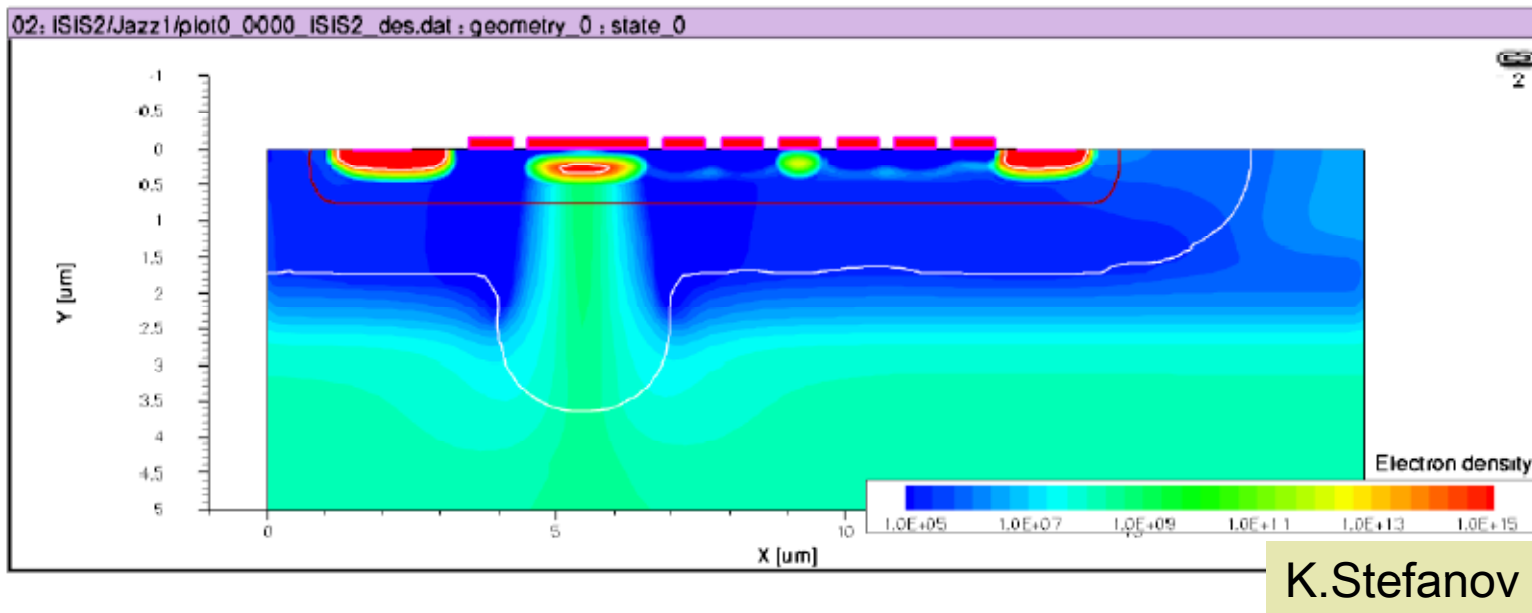
ISIS2 Variations

- Reset transistor
 - ◆ Surface
 - ◆ Buried channel
- Deep p+
 - ◆ With deep p+
 - ◆ Without deep p+
 - ◆ With deep p+ but no charge collection hole
 - ◆ Change in dopant concentrations of ~20%
- CCD gate width



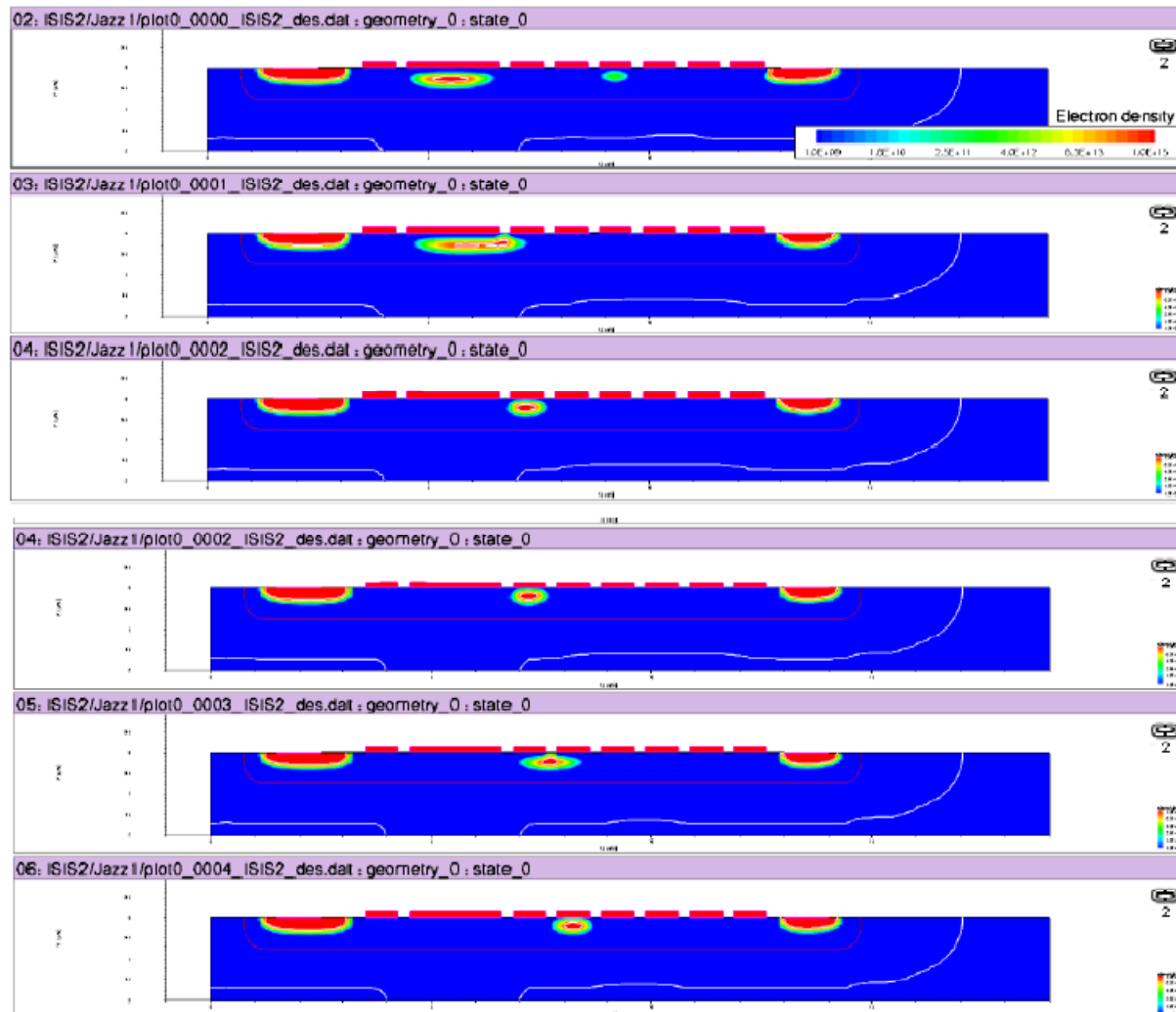
Charge Collection

- Performance extensively simulated
- Charge collection:



Charge transfer

- Simulated charge transfer to photogate and to storage cells – all function with high efficiency



K.Stefanov

Physics Studies

- LCFI vertexing package is actively used by all ILC detector concepts
- LCFI has strong participation in the ILC and SiD benchmarking studies
- Physics processes
 - ◆ $t\bar{t}$
 - ◆ ZHH
 - ◆ $ZH \rightarrow cc \nu\nu; cc qq; ee X$
 - ◆ $ee \rightarrow bb; cc$
 - ◆ $S_{\text{bottom}} \rightarrow \text{soft } b \text{ jets}$

Mechanical Studies

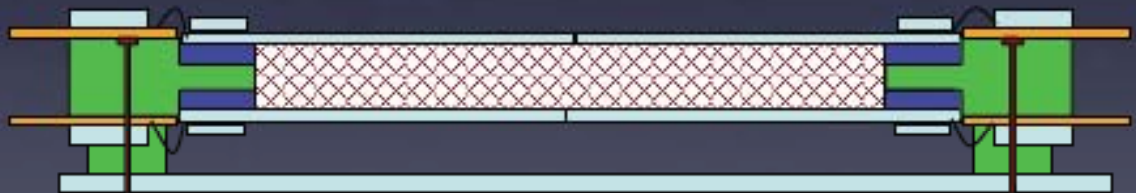
- 25 micron silicon on 1.5mm 8% SiC

- ▶ Very rigid
- ▶ Achieved 0.14% X_0



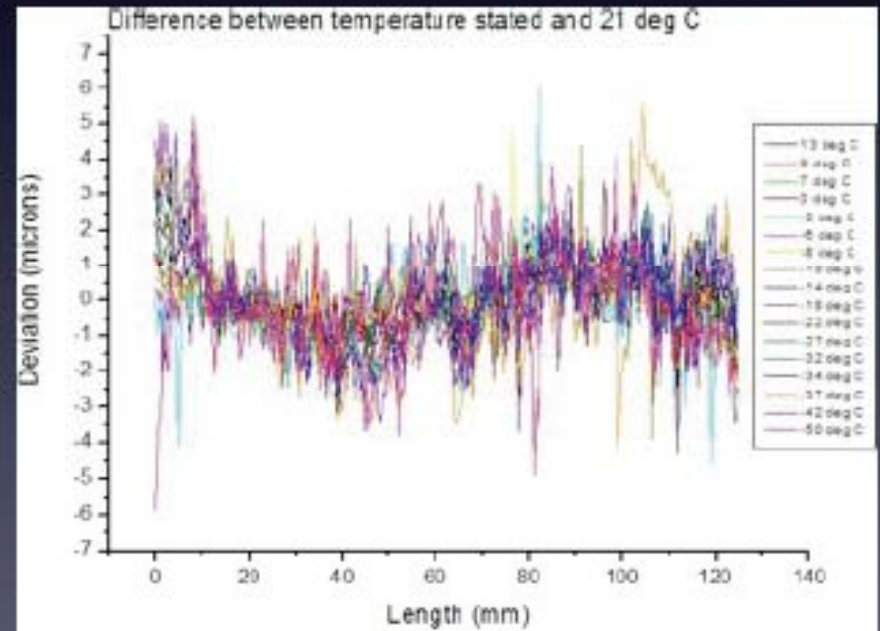
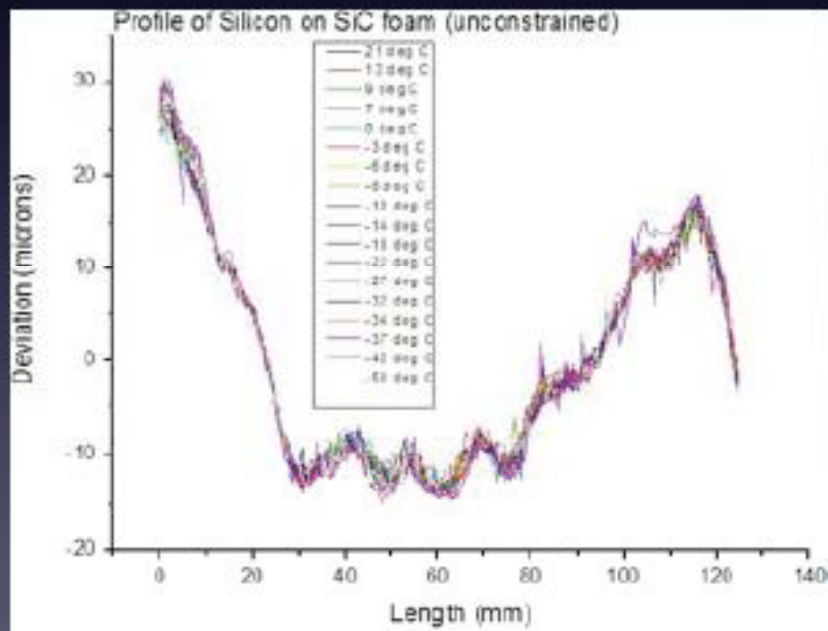
- 20 micron silicon sandwiching 1.5mm 2% carbon

- ▶ Could be double-sided
- ▶ Achieved 0.07% X_0



Mechanical Studies

- SiC Foam substrate ladder cooled
- Negligible thermal distortion over 70°C



Summary

- CPCCD demonstrated
 - ◆ Operation at 45 MHz with transformers
 - ◆ Low noise operation at 20 MHz
 - ◆ Operation with readout chip at 9 MHz, new readout chip under tests
 - ◆ 10 cm long sensors produced and tested
- ISIS proof of principle demonstrated
- ISIS2 ready for submission
- Good progress in Physics Studies and Mechanics
- Future uncertain.. But we hope to continue

Backups

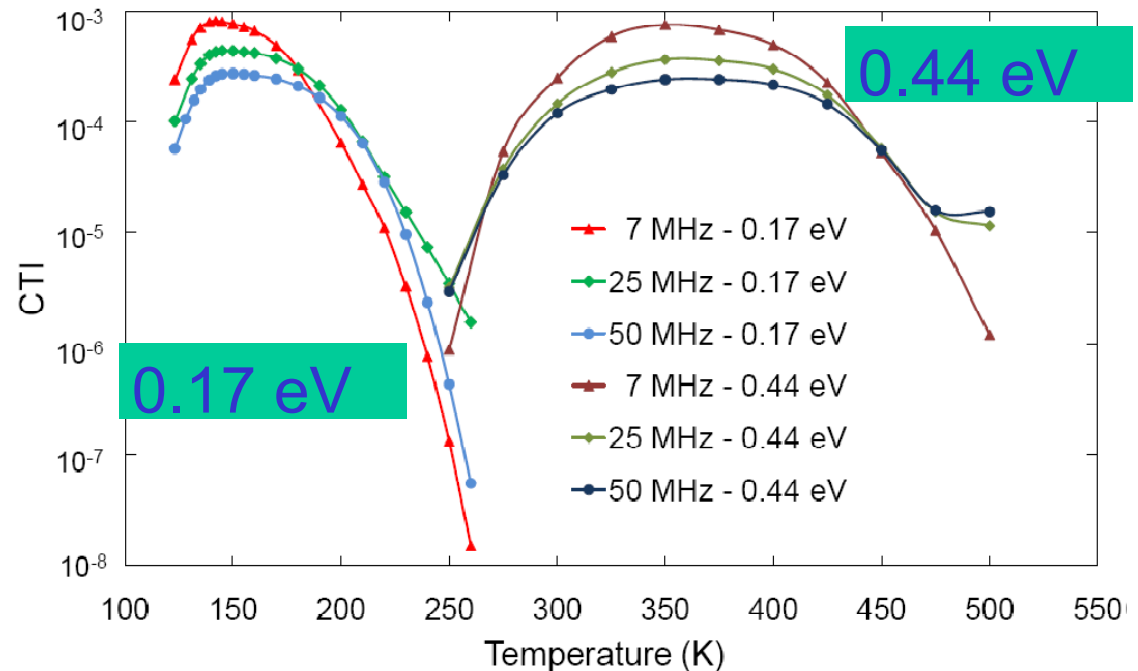
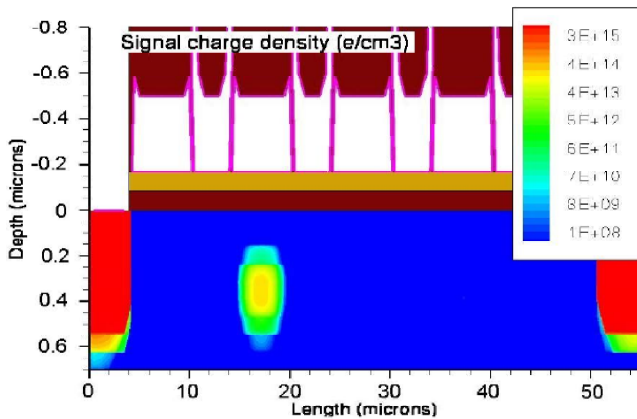
Radiation Damage: What to Expect?

At R-14 mm

- Pair background from Beamstrahlung
 - ◆ 10 MeV electrons, $3.5 \text{ /bx/cm}^2 \rightarrow 0.5 \cdot 10^{12} \text{ /year/cm}^2$ ($\rightarrow 15 \text{ krad/year}$)
 - ◆ Surface damage: accumulation of charge at SiO_2/Si interfaces
 - ◆ Bulk damage: traps & leakage current
- Neutrons
 - ◆ 1 MeV n; $0.01 \text{ /bx/cm}^2 \rightarrow 1.6 \cdot 10^9 \text{ /year/cm}^2$
 - ◆ Bulk damage
- Surface damage can be accommodated by adjustment of CCD biases
- Bulk damage translates to trap density
 - ◆ 0.17 eV trap; $3 \cdot 10^{11} \text{ /year/cm}^3$; caused by electrons
 - ◆ 0.44 eV trap; $4 \cdot 10^{10} \text{ /year/cm}^3$; caused by electrons and neutrons

Radiation Damage: Simulations

- ISE-TCAD simulations of charge propagation in the presence of traps
 - ◆ Charge trapped and later released: function of T and frequency
 - ◆ There is an optimum temperature window of low Charge Transfer Inefficiency (CTI) between $-50\text{ }^{\circ}\text{C}$ and $0\text{ }^{\circ}\text{C}$
- This should be confirmed experimentally in CPC2 and CPC-T



Irradiations of DALSA CCDs

- Study to verify rad hardness of non-overlapping polySi gates
 - ◆ Charge-up of SiO₂ insulation between gates
 - ◆ Relevant for ISIS technologies with small cells
- DALSA CCD survived 70 krad from ⁹⁰Sr beta source
 - ◆ No change in minimal clock amplitude

